

INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	Docket Number (Optional) TWI-12730	Application Number NEW 10/689,332
	Applicant(s) Minna Hovinen et al.	
	Filing Date HEREWITH	Group Art Unit Unknown 2872

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
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	*AB	4,636,088	01/13/1987	Rosencwaig et al.	374	5	05/21/1984
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	*AE	4,999,014	03/12/1991	Gold et al.	356	382	05/04/1989
	*AF	5,074,669	12/24/1991	Opsal	356	445	12/12/1989
	*AG	5,181,080	01/19/1993	Fanton et al.	356	381	12/23/1991
	*AH	5,298,970	03/29/1994	Takamatsu et al.	356	349	10/01/1992
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	*AO	6,535,285	03/18/2003	Opsal et al.	356	369	02/08/2000

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	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
M ↓	*AP	WO 99/02970	01/21/1999	PCT	G01N	21/21		
	*AQ	WO 00/68656	11/16/2000	PCT	G01J	4/00		

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M ↓	*AR	L. Zhou et al., "Use of a New Thermal Wave Technology for Ultra-Shallow Junction Implant Monitoring," <i>Proceedings of the X International Conference on Ion Implantation Technology</i> , June 1998, Kyoto (Japan), pp. 1-4.
	*AS	A. Selnick et al., "Quantitative Photothermal Characterization of Ion-Implanted Layers in Si," <i>25th Review of Progress in QNDE</i> , Snowbird (Utah), July 19-24, 1998, pp. 1-15.
	*AT	U.S. Patent Application No. 09/499,974, filed February 8, 2000, entitled "Combination Thermal Wave and Optical Spectroscopy Measurement System," (3 drawing pages included) by Jon Opsal et al., 29 pages in length.

Examiner SIDER	Date Considered 11/19/04
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	